



Atty. Dkt. No. 039262-0165

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Tadahiro OHMI et al  
Title: PLASMA PROCESSING METHOD AND METHOD FOR  
MANUFACTURING AN ELECTRONIC DEVICE  
Appl. No.: 10/594,895  
Filing Date: 11/07/2006  
Examiner: Valerie N. Brown  
Art Unit: 2829  
Confirmation Number: 8302

**AMENDMENT AND REPLY UNDER 37 CFR 1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Sir:

This communication is responsive to the Non-Final Office Action dated April 24, 2009, concerning the above-referenced patent application. Applicants have enclosed with this amendment a Petition for Extension of Time to make this response timely.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this document.

**Remarks/Arguments** begin on page 3 of this document.

Please amend the application as follows:

10/26/2009 SZEWDIE1 00000028 10594895

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